

**SCREEN Semiconductor Solutions Co., Ltd.**

## **SCREEN Signs Agreement with Applied Materials to Collaborate at the META Center**

Kyoto, Japan – January 14, 2020 – SCREEN Semiconductor Solutions Co., Ltd. (SCREEN SPE) announced it has signed an agreement with Applied Materials, Inc. (headquarters: Santa Clara, California, USA) to collaborate on process development at Applied’s new R&D facility – the Materials Engineering Technology Accelerator (META Center). The agreement brings together SCREEN SPE’s expertise in wafer cleaning technology with Applied’s leadership in materials engineering solutions.

### **Signing ceremony**

Right: Ellie Yieh  
Vice President for Advanced Product Technology Development  
Applied Materials, Inc.  
Left: Masato Goto  
Representative Director and President  
SCREEN Semiconductor Solutions Co., Ltd.

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Applied’s META Center is a unique facility aimed at speeding customer prototyping of new chip materials, process technologies and devices. It is located on the NY Center for Research, Economic Advancement, Technology, Engineering and Sciences (NY CREATES) campus in Albany, New York.

Under the agreement, SCREEN SPE will install an SU-3200 single-wafer cleaning system at the META Center. The SU-3200 will complement Applied’s state-of-the-art process systems currently running in the META Center and enable the companies to configure optimal cleaning technology for pre- and post-cleaning processes.

SCREEN SPE’s president Masato Goto expressed his excitement for the project. “It is very advantageous for SCREEN SPE to collaborate with Applied Materials at the META Center to optimize cleaning technology for the most advanced processes, including film formation, etching and ion implantation. Having access to such a cutting-edge facility as the META Center will help SCREEN SPE provide higher value semiconductor processes for our customers.”

Vice President for Advanced Product Technology Development within the New Markets and Alliances Group at Applied Materials, Ellie Yieh said, “The addition of SCREEN SPE’s wafer cleaning system strengthens the capabilities of the META Center and gives us more resources to help the industry accelerate development of new technologies from lab to fab. We look forward to collaborating with SCREEN SPE and others at the META Center to optimize processes for advanced chip designs.”

## **About SCREEN Semiconductor Solutions Co., Ltd.**

SCREEN Semiconductor Solutions has been established as a group company of SCREEN Holdings, inheriting the semiconductor equipment business from its predecessor, Dainippon Screen. SCREEN is a specialized manufacturer in various areas such as wafer cleaning equipment, lithography equipment and thermal anneals, and is one of the world’s top 10 equipment suppliers to the semiconductor manufacturing industry. For more information, please visit [www.screen.co.jp/eng/spe](http://www.screen.co.jp/eng/spe).

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